IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

oplicant:

Truskett et al.

App. No.:

10/687,519

GPAU:

1775

Filing Date:

10/16/2003

Examiner:

Turner, Archene A.

Dkt. No.:

P75-17-03

Conf. No.:

5222

For: LOW SURFACE ENERGY TEMPLATES

INFORMATION DISCLOSURE STATEMENT

Mail Stop AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

X Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449

Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information` Disclosure Statement is being filed: before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

the Commissioner is hereby authorized to charge any fees which may be required, or credit any overpayment, to Deposit Account Number 502650.

CERTIFICATE OF TRANSMISSION

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Signed:_

Typed Name: Katrina Prati

Date:

Respectfully Submitted,

Kenneth C. Brooks,

Reg. No. 38,393 Legal Department

Molecular Imprints, Inc.

P.O. Box 81536

Austin, TX 78758-1536

(512) 339-7760

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Sheet 1 of 3

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Complete if Known						
Application Number 10/687,519						
Filing Date	10/16/2003					
First Named Inventor	Truskett et al.					
Group Art Unit	1775					
Examiner Name	Turner, Archene A.					
Attorney Docket Number	P75-17-03					

	1	U.S. Patent Do	cument	U.S. PATENT DOCUMEN	T	Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number (if known)		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	C1	6,495,624	B1	Brown	12-17-2002	
	C2	6,447,919	B1	Brown et al.	09-10-2002	
	C3	5,523,878		Wallace et al.	06-04-1996	
	C4	5,937,758		Maracas et al.	08-17-1999	
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Examiner Signature					Date Considered	

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STA	TEMENT BY	ΑP	PLICANT	First Named Inventor	Truskett et al.	
				Group Art Unit	1775	
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Sheet	2	of	3	Attorney Docket Number	P75-17-03	

				FOREIGN	PATENT DOCUMENTS			
Examiner Initials*	Cite No.1	Office ³	Foreign Patent Documer Number ⁴	nt Kind Code⁵ (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T6
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				Application Number	10/687,519	
INF	ORMATION	DIS	CLOSURE	Filing Date	10/16/2003	
STA	TEMENT BY	/ AF	PPLICANT	First Named Inventor	Truskett et al.	
				Group Art Unit	1775	
	(use as many sheet	s as n	ecessary)	Examiner Name	Turner, Archene A.	
Sheet	3	of	3	Attorney Docket Number	P75-17-03	

OTHER PRIC	OR ART - I	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite, No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Parikh et al.," An Intrinsic Relationship between Molecular Structure in Self-Assembled n-Alkysiloxane	
	C6	Monolayers and Deposition Temperature," Journal of Phys. Chem., pp7577-7590, 1994.	
1.11.		Sagiv, J., "Organized Monolayers by Adsorption. 1. Formation and Structure of Oleophobic Mixed	
	C7	Monolayes and Solid Surfaces," Journal of the American Chemical Society, vol. 102, pp. 92-98, January 2, 1980.	
		Srinivasan et al.," Alkyltrichlorosilane-Based Self-Assembled Monolayer Films for Stiction Reduction in	
	C8	Silicon Micromachines," Journal of Microelectromechanical Systems, Vol. 7, No. 2, p. 252-260, June 1, 1998.	
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Group	Art Unit	1775					
Examiner Name Turner, Archene A.							
Attorn	ey Docket Number	P75-17-03					

				U.S. PATENT DOCUMEN	TS	
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	D1	3,527,062		Bilinski et al.	09-08-1970	
	D2	3,783,520		King	01-08-1974	
	D3	3,807,027		Heisler	04-30-1974	
	D4	3,807,029		Troeger	04-30-1974	
	D5	3,811,665		Seelig	05-21-1974	
	D6	4,062,600		Wyse	12-13-1977	
•	D7	4,070,116		Frosch et al.	01-24-1978	
	D8	4,098,001		Watson	07-04-1978	
	D9	4,119,688		Hiraoka	10-10-1978	
	D10	4,119,688	1	Hiraoka	10-10-1978	
	D11	4,155,169		Drake et al.	05-22-1979	
	D12	4,201,800		Alcorn et al.	05-06-1980	
	D13	4,202,107	-	Watson	05-13-1980	
	D14	4,267,212		Sakawaki	05-12-1981	
	D15	4,326,805		Feldman et al.	04-27-1982	
······································	D16	4,337,579		De Fazio	07-06-1982	
	D17	4,355,469		Nevins et al.	10-26-1982	
•	D18	4.414.750		De Fazio	11-15-1983	
	D19	4,426,247		Toshiakai et al.	01-17-1984	
	D20	4,440,804		Milgram	04-03-1984	
	D21	4,451,507		Beltz et al.	05-29-1994	
	D22	4,507,331	·	Hiraoka	03-02-1985	
	D23	4,552,832	<u> </u>	Blume et al.	11-12-1985	
	D22	4,552,833		Ito et al.	11-12-1985	-
	D25	4,600,309	1	Fay	07-15-1986	
	D26	4,610,442	-	Oku et al.	09-09-1986	
	D27	4,657,845	<u> </u>	Frechet et al.	04-04-1987	
	D28	4,692,205		Sachdev et al.	09-08-1987	
	D29	4,694,703	1	Routson	09-22-1987	
	D30	4,707,218		Giammarco et al.	11-17-1987	
	D31	4,724,222		Feldman	02-09-1988	****
	D32	4,737,425		LIN et al.	04-12-1988	
	D33	4,763,886		Takei	08-16-1988	
	D34	4,808,511	1	Holmes	02-28-1989	
Examiner Signature			 _		Date Considered	

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examiner nitials*	Cite No. ¹	I		T Name of Detector or Articont	Date of Publication of	Pages, Columns, Lines,
		Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	D35	4,826,943		Ito et al.	05-02-1989	
	D36	4,846,931		Gmitter et al.	07-11-1989	
	D37	4,848,911		Uchida et al.	07-18-1989	
	D38	4,857,477		Kanamori	08-15-1989	
	D39	4,883,561		Gmitter et al.	11-28-1989	
	D40	4,891,303		Garza et al.	01-02-1990	
	D41	4,908,298		Hefferon et al.	03-13-1990	
	D42	4,919,748		Bredbenner et al.	04-24-1990	
	D43	4,921,778		Thackeray et al.	05-01-1990	
	D44	4,929,083		Brunner	05-29-1990	
	D45	4,931,351		McColgin et al.	06-05-1990	
	D46	4,964,945		Calhoun	10-23-1990	
	D47	4,976,818		Hashimoto et al.	12-11-1990	
	D48	4,980,316		Huebner	12-25-1990	
· ·	D49	4,999,280		Hiraoka	03-12-1990	
	D50	5,053,318		Guila et al.	10-01-1991	
	D51	5,063,321		Carter	11-05-1991	
	D52	5,071,694		Uekita et al.	12-10-1991	
	D53	5,072,126		Progler	12-10-1991	
	D54	5,073,230		Maracas et al.	12-17-1991	
	D55	5,074,667		Miyatake	12-24-1991	
	D56	5,108,875		Thackeray et al.	04-28-1992	
	D57	5,110,514		Soane	05-05-1992	
	D58	5,126,006		Cronin et al.	06-30-1992	
	D59	5,148,036		Matsugu et al.	09-15-1992	
	D60	5,148,037		Suda et al.	09-15-1992	
	D61	5,151,754		Ishibashi et al.	09-29-1992	
	D62	5,169,494		Hashimoto et al.	12-08-1992	
	D63	5,173,393		Sezi et al.	12-22-1992	
	D64	5,179,863		Uchida et al.	01-19-1993	
	D65	5,198,326		Hashimoto et al.	03-30-1993	
	D66	5,204,739		Domenicali	04-20-1993	
	D67	5,212,147		Sheats	05-18-1993	
	D68	5,234,793		Sebald et al.	08-10-1993	
Examiner					Date	

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Complete if Known Substitute for form 1449A/PTO 10/687,519 **Application Number** INFORMATION DISCLOSURE Filing Date 10/16/2003 STATEMENT BY APPLICANT **First Named Inventor** Truskett et al. Group Art Unit 1775 (use as many sheets as necessary) Turner, Archene A. **Examiner Name**

16

of

	Υ	U.S. Patent Do		U.S. PATENT DOCUMENTS		Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	D69	5,240,550		Boehnke et al.	08-31-1993	
	D70	5,240,878		Fizsimmons et al.	08-31-1993	
	D71	5,242,711		DeNatale et al.	09-07-1993	
	D72	5,244,818		Jokerst et al.	09-14-1993	
	D73	5,270,984	Α	Mine	12-14-1993	
	D74	5,277,749		Griffith et al.	01-11-1994	
	D75	5,314,772		Kozicki et al.	05-24-1994	
	D76	5,318,870		Hartney	06-07-1994	
	D77	5,324,683		Fitch et al.	06-28-1994	
	D78	5,328,810		Lowrey et al.	07-12-1994	
	D79	5,330,881		Sidman et al.	07-19-1994	
	D80	5,348,616		Hartman et al.	09-20-1994	
	D81	5,362,606		Hartney et al.	11-08-1994	
	D82	5,366,851		Novembre	11-22-1994	
	D83	5,374,454		Bickford et al.	12-20-1994	
	D84	5,376,810		Hoenk et al.	12-27-1994	
	D85	5,380,474		Rye et al.	01-10-1995	
	D86	5,392,123		Marcus et al.	02-21-1995	
	D87	5,417,802		Obeng	05-23-1995	
	D88	5,421,981		Leader et al.	06-06-1995	
	D89	5,422,295		Choi et al.	06-06-1995	
	D90	5,424,549		Feldman	06-13-1995	
	D91	5,425,964		Southwell et al.	06-20-1995	
	D92	5,431,777		Austin et al.	07-11-1995	
	D93	5,439,766		Day et al.	08-08-1995	
	D94	5,452,090		Progler et al.	09-19-1995	
	D95	5,453,157		Jeng	09-26-1995	
	D96	5,458,520		DeMercurio et al.	10-17-1995	
	D97	5,468,542		Crouch	11-21-1995	
	D98	5,515,167		Ledger et al.	05-07-1996	
	D99	5,527,662		Hashimoto et al.	06-18-1996	
	D100	5,545,367		Bae et al.	08-13-1996	
	D101	5,566,584		Briganti	10-22-1996	
	D102	5,633,505		Chung et al.	05-27-1997	
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Examiner Initials*		Kind Code ² Number (<i>if known</i>)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear		
	D103	5,654,238	Cronin et al.	08-05-1997			
	D104	5,669,303	Maracas et al.	09-23-1997			
	D105	5,670,415	Rust	09-23-1997			
	D106	5,700,626	Lee et al.	12-23-1997			
	D107	5,723,176	Keyworth et al.	03-03-1998			
	D108	5,724,145	Kondo et al.	03-03-1998			
	D109	5,736,424	Prybyla et al.	04-07-1998			
	D110	5,743,998	Park	04-28-1998			
	D111	5,747,102	Smith et al.	05-05-1998			
	D112	5,753,014	Van Rijn	05-19-1998			
	D113	5,760,500	Kondo et al.	06-02-1998			
	D114	5,779,799	Davis	07-14-1998			
	D115	5,802,914	Fassler et al.	09-08-1998			
	D116	5,855,686	Rust	01-05-1999			
	D117	5,877,036	Kawai	03-02-1999	"		
	D118	5,877,861	Ausschnitt et al.	03-02-1999			
	D119	5,888,650	Calhoun et al.	03-30-1999			
	D120	5,895,263	Carter et al.	04-20-1999			
	D121	5,907,782	Wu	05-25-1999			
	D122	5,912,049	Shirley	06-15-1999			
	D123	5,926,690	Toprac et al.	07-20-1999			
	D124	5,942,871	Lee	08-24-1999			
	D125	5,948,219	Rohner	09-07-1999			
	D126	5,948,570	Kornblit et al.	09-07-1999			
	D127	5,952,127	Yamanaka	09-14-1999			
	D128	6,033,977	Gutsche et al.	03-07-2000			
	D129	6,035,805	Rust	03-14-2000			
	D130	6,038,280	Rossiger et al.	03-14-2000			
	D131	6,046,056	Parce et al.	04-04-2000			
	D132	6,051,345	Huang	04-18-2000			
	D133	6,074,827	Nelson et al.	06-13-2000			
	D134	6,091,485	Li et al.	07-18-2000			
	D135	6,096,655	Lee et al.	08-01-2000			
	D136	6,125,183	Jiawook et al.	09-26-2000			
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Complete if Known Substitute for form 1449A/PTO **Application Number** 10/687.519 INFORMATION DISCLOSURE Filing Date 10/16/2003 STATEMENT BY APPLICANT Truskett et al. **First Named Inventor** 1775 Group Art Unit (use as many sheets as necessary) Turner, Archene A. **Examiner Name** 5 16 P75-17-03 **Sheet** of **Attorney Docket Number**

	T	U.S. Patent D		I	Date of Publication of	Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	D137	6,150,231		Muller et al.	11-21-2000	
	D138	6,150,680		Eastman et al.	11-21-2000	
	D139	6,188,150	B1	Spence	02-13-2001	
	D140	6,204,922	B1	Chalmers	03-20-2001	
	D141	6,245,581	B1	Bonser et al.	06-12-2001	
	D142	6,274,294	B1	Hines	08-14-2001	
	D143	6,326,627	B1	Putvinski et al.	12-04-2001	
	D144	6,329,256	B1	Ibok	12-11-2001	
	D145	6,387,783		Furukawa et al.	05-14-2002	
	D146	6,388,253	B1	Su	05-14-2002	
	D147	6,391,798	B1	DeFelice et al.	05-21-2002	
	D148	6,411,010	B1	Suzuki et al.	06-25-2002	
	D149	6,455,411	B1	Jiang et al.	09-24-2002	
	D150	6,467,761	B1	Amatucci et al.	10-22-2002	
	D151	6,482,742	B1	Chou	11-19-2002	
	D152	6,489,068	B1	Kye	12-03-2002	
	D153	6,514,672	B2	Young et al.	02-04-2003	
	D154	6,534,418	B1	Plat et al.	03-18-2003	
	D155	6,541,360	B1	Plat et al.	04-01-2003	
	D156	6,561,706		Singh et al.	05-13-2003	
	D157	6,565,928	B2	Sakamoto et al.	05-20-2003	
	D158	6,632,742	B2	Yang et al.	10-14-2003	
	D159	6,635,581	B2	Wong	10-21-2003	
	D160	6,646,662	B1	Nebashi et al.	11-11-2003	
	D161	6,677,252	B2	Marsh	01-13-2004	
	D162	6,696,220	B2	Bailey et al.	02-24-2004	
	D163	6,703,190	B2	Elian	03-09-2004	
	D164	6,713,238	B1	Chou et al.	03-30-2004	
	D165	6,716,767	B2	Shih et al.	04-06-2004	
	D166	6,719,915	B2	Willson et al.	04-13-2004	
	D167	6,730,256	B1	Bloomstein et al.	05-04-2004	
	D168	6,737,202	B2	Gehoski et al.	05-18-2004	
	D169	6,743,713	B2	Mukherjee-Roy et al.	06-01-2004	
	D170	6,767,983	B1	Fujiyama et al.	07-27-2004	
Examiner Signature					Date Considered	

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		U.S. Patent Doo		N	Date of Publication of	Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	D171	6,770,852	B1	Steger	08-03-2004	
	D172	6,776,094	B1	Whitesides et al.	08-17-2004	
_	D173	6,777,170	B1	Bloomstein et al.	08-17-2004	
	D174	2002/0093122	A1	Choi et al.	07-18-2002	
	D175	2002/0094496	A1	Choi et al.	07-18-2002	
	D176	2002/0098426	A1	Sreenivasan et al.	07-25-2002	
	D177	2002/0132482		Chou	09-19-2002	
	D178	2002/0150398	A1	Choi et al.	10-17-2002	
	D179	2002/0167117		Chou	11-14-2002	
	D180	2003/0080471		Chou	05-01-2003	
	D181	2003/0081193		White et al.	05-01-2003	
	D182	2003/0113638	A1	Mancini et al.	06-19-2003	
	D183	2003/0129542	A1	Shih et al.	07-10-2003	
	D184	2003/0205657	A1	Voisin	11-06-2003	
	D185	2003/0205658	A1	Voisin	11-06-2003	
	D186	2003/0215577	A1	Willson et al.	11-20-2003	
	D187	2003/0235787	A1	Watts et al.	12-25-2003	
	D188	2004/0008334	A1	Sreenivasan et al.	01-15-2004	
	D189	2004/0009673	A1	Sreenivasan et al.	01-15-2004	
	D190	2004/0010341	A1	Watts et al.	01-15-2004	
	D191	2004/0029041	A1	Shih et al.	02-12-2004	
	D192	2004/0036201	A1	Chou et al.	02-26-2004	
	D193	2004/0053146	A1	Sreenivasan et al.	03-18-2004	
	D194	2004/0086793	A1	Sreenivasan et al.	05-06-2004	
	D195	2004/0089979	A1	Rubin	05-13-2004	
	D196	2004/0090611	A1	Choi et al.	05-13-2004	
	D197	2004/0104641	A1	Choi et al.	06-03-2004	
	D198	2004/0112861	A1	Choi et al.	06-17-2004	
	D199	2004/0112862	A1	Willson et al.	06-17-2004	
	D200	2004/0116548	A1	Willson et al.	06-17-2004	
	D201	2004/0124566	A1	Sreenivasan et al.	07-01-2004	
	D202	2004/0141163	A1	Bailey et al.	07-22-2004	
	D203	2004/0141168	A1	Sreenivasan et al.	07-22-2004	
	D204	2004/0149687	A1	Choi et al.	08-05-2004	
Examiner Signature					Date Considered	_

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Application Number	10/687,519				
Filing Date	10/16/2003				
First Named Inventor	Truskett et al.				
Group Art Unit	1775				
Examiner Name	Turner, Archene A.				
Attorney Docket Number	P75-17-03				

				U.S. PATENT DOCUMENTS	S	
Examiner nitials*	Cite No.1	U.S. Patent Doo	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	D205	2004/0163563	A1	Sreenivasan et al.	08-26-2004	
	D206	2004/0168586	A1	Bailey et al.	09-02-2004	
	D207	2004/0168588	A1	Choi et al.	09-02-2004	
	D208	2004/0168613	A1	Nguyen	09-02-2004	-
	D209	2004/0169441	A1	Choi et al.	09-02-2004	
	D210	2004/0170770	A1	Nguyen	09-02-2004	
	D211	2004/0170771	A1	Bailey et al.	09-02-2004	
	D212	2004/0188381	A1	Sreenivasan et al.	09-30-2004	
	D213	2004/0189994	A1	Sreenivasan et al.	09-30-2004	
	D214	2004/0189996	A1	Sreenivasan et al.	09-30-2004	
	D215	2004/0200411	A1	Willson et al.	10-14-2004	
	D216	2004/0202865		Homola et al.	10-14-2004	
	D217	2004/0209177	A1	Sreenivasan et al.	10-21-2004	
	D218	6,383,928	B1	Eissa	05-07-2002	
Examiner Signature					Date Considered	

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Substitute	for form 1449A/PT	0		Complete if Known		
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			-	OREIGN	PATENT DOCUMENTS			
Examiner Initials*	Cite No.1	Office ³		ind Code ⁵ if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Т ⁶
	D219	DE	19648844		Muller et al.	09-18-1997		
	D220	EP	733455		Anderhub et al.	09-25-1996	_	\perp
	D221	JP	02-24848		Kamio	01-26-1990		\perp
	D222	JP	02-92603		Kurikawa et al	04-03-1990		
	D223	JP	55-88332		Masahiro	07-14-1980		\perp
	D224	JP	57-7931		Hirakawa et al.	01-16-1982		
	D225	JP	63-138730		Koji	06-10-1988		
	D226	wo	00/21689		Chou et al.	04-20-2000		
	D227	wo	00/54107		Willson et al.	09-14-2000		
	D228	wo	01/33232		Andeen et al.	05-10-2001		
	D229	wo	01/33300		Choi	05-10-2001		
	D230	wo	01/47003	A2	Steiner et al.	06-28-2001		
	D231	wo	01/69317		Montelius et al.	09-20-2001		I
	D232	wo	01/79589		Hallberg	10-25-2001		T
	D233	wo	01/79592		Hallberg et al.	10-25-2001		
	D234	wo	2004/044651		Choi et al.	05-27-2004		T
	D235	wo	92/17883		Olsson	10-15-1992		T
	D236	wo	98/10121		Olsson et al.	03-12-1998		T
	D237	wo	99/45753	T .	Wikström	09-10-1999		
	D238	wo	99/63535		Olsson	12-09-1999		
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INF	ORMATION	DISC	LOSURE	Filing Date	10/16/2003
STATEMENT BY APPLICANT				First Named Inventor	Truskett et al.
				Group Art Unit	1775
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Sheet	9	of	16	Attorney Docket Number	P75-17-03

OTHER PRI	OR ART - I	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	D239	Abstract of Japanese Patent 02-24848, January 26, 1990	
	D240	Abstract of Japanese Patent 02-92603, August 12, 2004	
	D241	Abstract of Japanese Patent 55-88332, April 14, 2004	
	D242	Abstract of Japanese Patent 57-7931, April 14, 2004	
	D243		
	D244	ANANTHASURESH et al., "Strategies for Systematic Synthesis of Compliant Mems.", DSC-Vol. 55-2, Dynamic Systems and Control: Volume 2, pp. 677 – 686, November 1, 1994.	
!	D245	ARAI et al., "Calibration and Basic Motion of Micro Hand Module.", IEEE, January 1, 1993, pp. 1660-1665.	
	D246	Arai et al., "Development of a New Parallel Manipulator with Fixed Linear Actuator.", In Proceedings of Japan/USA Symposium on Flexible Automation, January 1, 1996, Vol. 1, ASME, New York, pp. 145-149.	
	D247	BAILEY et al., "Imprint Lithography Templates having Alignment Marks," U.S. Patent Application 10/666,527, Filed with USPTO Sept. 18, 2003	
	D248	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 – 62 , January 1, 2002, pp. 407-413.	
	D249	CHERALA et al., "Applying Imprinting Material to Substrates Employing Electromagnetic Fields," U.S. Patent Application 10/687,562, Filed with USPTO Oct. 16, 2003	

Examiner	Date
Signature	Considered

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Substitute	e for form 1449B/P	то		Complete if Known		
				Application Number	10/687,519	
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OTHER PRIO	R ART - N	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	D250	Sreenivasan et al., "A Conforming Template for Patterning Liquids Disposed on Substrates." U.S. Patent Application 10/614,716. Filed with USPTO on July 7, 2003.	
	D251	CHOI et al., "Method and System of Automatic Fluid Dispensing for Imprint Lithography Processes." U.S. Patent Application Publication 2002/0094496. Published on July 18, 2002.	
	D252		
	ļ	Chou, Ultrafast and Direct Imprint of Nanostructures in Silicon, Nature, Col. 417, (June 2002), pp. 835-837.	
	D253	CIBA SPECIALTY CHEMICALS, "What is UV Curing?", www.cibasc.com/image.asp?id=4040	
	D254	FELDMAN et al., "Wafer Chuck Magnification Correction in X-Ray Lithography.", J. Vac. Sci. Technol. B 16(6), November 1, 1998, pp. 3476 – 3479.	
	D255	FEYNMAN, "There's Plenty of Room at the Bottom.", International Appl. No. PCT/US2002/015551	
	D256	GOLDFARB et al., "A Well-Behaved Revolute Flexure Joint for Compliant Mechanism Design.",	
	D257	GOLDFARB et al., "Compliant Micromanipulator Design for Scaled Bilateral Telemanipulation of Small-Scale Environments.", ASME International Mechanical Engineering Conference and Exposition, November 1, 1998, DSC-Vol. 64, pp. 213-218.	
	D258	HASHIMOTO et al., "Design and Characteristics of a Parallel Link Complaint Wrist." IEEE, May 1, 1994, Department of Mechanical Engineering, Kagoshiam University, pp. 2457-2462.	
	D259	HEIDARI, "Nanoimprint Lithography at the 6 in. Wafer Scale.", J. Vac. Sci. Technol. B 18 (6), November 1, 2000, pp. 3557 – 3560.	
	D260		
		HEXAPODS, "G1000-PS Power Series", www.hexapods.com.	

Examiner	Date	
Signature	Considered	

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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OTHER PRIC	OR ART - I	NON PATENT LITERATURE DOCUMENTS	
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	D261	HEXEL COPORATION, "Tornado 2000 System Specifications.", www.hexel.com, November 12, 1999.	
	D262	HIRAI et al., "Mold Surface Treatment for Imprint Lithography.", Journal of Photopolymer Science and Technology, August 1, 2001, Vol. 14, No. 3, pp. 457-462.	
	D263	HOGAN et al., "Impedance Control: An Approach to Manipulation: Part 1- Theory.", Journal of Dynamic Systems, Measurement, and Control, March 1, 1985, Vol. 107, pp. 1-7.	
	D264	HOLLIS et al., "A Six-Degree-of-Freedom Magnetically Levitated Variable Compliance Fine-Motion Wrist: Design, Modeling, and Control.", IEEE Transactions on Robotics and Automation, June 1, 1991, Vol 7., No. 3, pp. 320 – 332.	
	D265	HOWELL et al., "A Loop-Closure Theory for the Analysis and Synthesis of Compliant Mechanisms.", Journal of Mechanical Design, March 1, 1996, Vol. 188, pp. 121-125.	
	D266	HU et al., "Fluorescence Probe Techniques (FPT) for Measuring the Relative Efficiencies of Free-Radical Photoinitiators.", Macromolecules, May 29, 1998, 31, pp. 4107-4113.	
	D267	International Application No. PCT/US2002/015551, "Communication Relating to the Results of the Partial International Search."	
	D268	International Search Report for PCT/US 00/30041, October 18, 2001.	
	D269		
	D270	International Search Report for PCT/US 01/26049, February 19, 2002 JOHNSON et al., "Advances in Step and Flash Imprint Lithography.", SPIE Microlithography Conference, February 23, 2003.	
	D271	KANETOMO et al., "Robot for Use in Ultrahigh Vacuum.", Solid State Technology, August 1, 1997, pp. 63-72.	

Examiner	Date	
Signature	Considered	

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	D272	KIM et al., "High-precision Magnetic Levitation Stage for Photolithography.", Precision Engineering, April 1, 1998, Vol 22., No. 2, pp. 66 – 77.	
	D273	KOSEKI, "Design and Accuracy Evaluation of High-Speed and High Precision Parallel Mechanism.", Proc. Of IEEE, January 1, 1998, Intl. Conf. on Robotics & Automation, pp. 1340-1345.	
	D274	LEE et al., "An Ultraprecision Stage for Alignment of Wafers in Advanced Microlithography.", Precision Engineering, September 1, 1997, pp. 113-122.	
	D275	LEE et al., "Ultra Precision Positioning System for Servo Motor-piezo Actuator Using the Dual Servo Loop and Digital filter Implementation.", American Society for Precision Engineering, January 1, 1998, pp. 287-290.	
	D276	LUCAS AEROSPACE, Free-Flex ® Pivot Catalog, January 1, 1999	
	D277	MANSKY et al., "Large-Area Domain Alignment in Block Copolymer Thin Films Using Electric Fields.", Macromolecules, June 9, 1998, Vol. 31, No. 13, pp. 4399-4401.	
	D278	MCMACKIN et al., "A Method of Creating a Turbulent Flow of Fluid between a Mold and a Substrate," U.S. Patent Application 10/898,034, Filed with USPTO July 23, 2004.	
	D279	MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate," U.S. Patent Application 10/898,037, Filed with USPTO July 23, 2004.	
	D280	MCMACKIN et al., Single Phase Fluid Imprint Lithography Method," U.S. Patent Application 10/677,639, Filed with USPTO Oct. 16, 2003.	
	D281	MERLET, "Parallel Manipulators: State of the Art and Perspectives.", Advanced Robotics, January 1, 1994, Vol. 8, pp. 589-596.	
	D282	MITTAL, "Precision Motion Control of a Magnetic Suspension Actuator Using a Robust Nonlinear Compensation Scheme.", IEE/ASME Transactions on Mechatronics., December 1, 1997, Vol. 2., No. 4, pp. 268-280	

Examiner		Date	
Signature	·	Considered	<u></u>

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•				Application Number	10/687,519	
INFO	DRMATION I	DIS	CLOSURE	Filing Date	10/16/2003	
STATEMENT BY APPLICANT			PPLICANT	First Named Inventor	Truskett et al.	
				Group Art Unit	1775	
(use as many sheets as necessary)			ecessary)	Examiner Name	Turner, Archene A.	
Sheet	13	of	16	Attorney Docket Number	P75-17-03	

OTHER PRI	OR ART - I	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	D283		
	-	NERAC.COM Retro Search, "Multi-Layer Resists.", September 2, 2004.	┼
	D284		
		NERAC.COM Retro Search, "Reduction of Dimension of Contact Holes.", August 31, 2004.	╫┈
	D285		
	_	NERAC.COM Retro Search, "Trim Etching of Features Formed on an Organic Layer.", September 2, 2004.	╄
	D286	OHYA et al., "Development of 3-DOF Finger Module for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Intl. Conf. on Intelligent Robots and Systems, pp. 894-899.	
	D287	OTTO et al., "Step and Repeat UV-Nanoimprint Lithography: Material Issues.", NNT02 San Francisco, December 11, 2002.	
	D288	PAPIRER et al., "Abstract of The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography.", Journal of Colloid and Interface Science 159, August 1, 1993, pp. 238-242.	
	2000		
	D289	PAROS et al., "How to design Flexure Hinges.", Machine Design, November 25, 1965, pp 151-156.	Ŀ
	D290	PENG et al., "Compliant Motion Control of Kinematically Redundant Manipulators.", IEEE Transactions on Robotics and Automation, December 1, 1993, Vol. 9, No. 6, pp.831-837.	
	D291	PERNETTE et al., "Design of Parallel Robots in Microbotics.", Robotica, January 1, 1997, Vol. 15, pp 417-420.	
	D292		
		PHYSIK INSTRUMENTS, PI Online-Catalog, 1999, from www.physikinstruments.com	_
	D293		
		PHYSIK INSTRUMENTS, Product Catalog for Micropositioning, 1997	

Examiner	Date	
Signature	Considered	

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OTHER PRIC	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*			T ²			
	D294	RAIBERT et al., "Hybrid Position/Force Control of Manipulators.", Journal of Dynamic Systems, Measurement, and Control, June 1, 1981, Vol. 102, pp. 126 – 133.				
	D295	RONG et al., "Design and Analysis of Flexure-Hinge Mechanism Used in Micro-Positioning Stages.", ASME, January 1, 1994, Vol. 2, pp. 979-985.				
	D296	RONG et al., "Dynamics of Parallel Mechanism with Direct Compliance Control.", IEEE, January 1, 1997, pp. 1753-1758.				
	D297	ROOS et al., "Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing.", Proceedings of SPIE, October 1, 2001, Vol. 4343, pp. 427-435.				
	D298	RUCHHOEFT et al., "Patterning Curved Surfaces: Template Generation by Ion Beam Proximity Lithography and Relief Transfer by Step and Flash Imprint Lithography.", Journal of Vacuum Science and Technology, pp. 1-17.				
	D299	SLOCUM, "Precision Machine Design: Macromachine Design Philosophy and Its Applicability to the Design of Micromachines.", Micro Electro Mechanical Systems, February 4, 1992.				
	D300	SOWAH, Diamond Used to Break the Mould [online], Sept, 18, 2002, [Retrieved on Sept. 2, 2003.] Retrieved from the Internet: <url: eetuk.com="" http:="" showarticle.jhtml?articleid="19203691">.</url:>				
	D301	SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks," U.S. Patent Application 10/864,214 Filed with USPTO June 9, 2004.				
	D302	STEWART, "A Platform With Six Degrees of Freedom.", Proc Instn Mech Engrs, May 28, 1965, Vol 180, Pt1, No. 15, pp. 371-378.				
	D303					
	D304	STIX, "Getting More from Moores", Scientific American SUNG et al., "Abstract of Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication", Elsevier Science B.V., July 1, 2003, Vol. 255, no. 7				

Examiner	,	Date	
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	D305	SUNG et al., "Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication.", Elsevier Science B.V., July 1, 2003, Vol. 255, No. 7, pp. 808-818.			
	D306	TAJBAKHSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.			
	D307	TANIKAWA et al., "Development of Small-sized 3 DOF Finger Module in Micro Hand for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Intl. conf. on Intelligent Robots and Systems, pp. 876-881.			
	D308	TOMITA et al., "A 6-axes Motion Control Method for Parallel-Linkage-Type Fine Motion Stage.", JSPE-58-04, pp. 118-124.			
	D309	Translation of Japanese Patent 02-24848, January 26, 1990.			
	D310	Translation of Japanese Patent 02-92603, April 3, 1990.			
	D311	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com, January 1, 2001.			
	D312	US Application No. 10/375,817, Filed 02-27-2003, NGUYEN et al., "Method to Reduce Adhesion between a Polymerizable Layer and a Substrate Employing a Flourine-Containing Layer."			
	D313	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."			
	D314	US Application No. 10/735,110, Filed 12-12-2003, NIMMAKAYALA et al., "Magnification Correction Employing Out-of-Plane Distortion of a Substrate."			
	D315	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."			

Examiner	Date	
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*			T²		
	D316	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."			
	D317	US Application No. 10/806,956, Filed 03-23-2003, CHOI et al., "An Apparatus to Control Displacement of a Body Spaced-Apart from a Surface."			
	D318	US Applications No. 10/194,991, Filed 07-11-2002, SREENIVASAN et al., "Step and Repeat Lithography Processes."			
	D319	US Applications No. 10/687,519, Filed 10-16-2003, NGUYEN et al., "Low Surfaced Energy Template."			
	D320	VANDERBILT UNIVERSITY OFFICE OF TRANSFER TECHNOLOGY; VU9730 Specifications for Improved Flexure Device; 2001, 25, 192-199.			
	D321	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.			
	D322	WILLIAMS et al., "Six Degree of Freedom Mag-Lev Stage Development.", SPIE, January 1, 1997, Vol. 3051, pp. 856-867.			
	D323	WILLSON et al., "Step and Flash Imprint Lithography", U.S. Patent Application 10/806,051, Filed with USPTO March 22, 2004.			
	D324	WU, "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography.", J. Vac. Sci. Technol., November 1, 1998, B 16(6), pp. 3825-3829.			
	D325	XU et al., "Materials for Imprint Lithography," U.S. Patent Application 10/784,911, Filed with USPTO Feb. 23, 2004.			
	D326	XU et al., "Methods for Fabricating Patterned Features Utilizing Imprint Lithography,: U.S. Patent Application 10/694,284, Filed with USPTO Oct., 27, 2003.			

Examiner	 	Date	
Signature		Considered	i

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